## **AMENDMENTS TO THE CLAIMS**

The following listing of claims will replace all prior versions and listings of claims in the application.

## **LISTING OF CLAIMS**

- 1. (Currently amended) A device manufacturing apparatus comprising:
- a discharge head for discharging a droplet containing a functional material;
- a stage for supporting a substrate on which said droplet is discharged, and which is capable of moving relative to said discharge head;
  - a carrier for carrying said substrate;
- a detector for detecting a discharge condition of said droplet which is discharged from a discharge nozzle formed in said discharge head;
- a driving device for moving said discharge head with respect to said detector; and
- a controller for executing a detection operation by said detector during [a carrying operation] loading and unloading operations of said substrate, wherein[\*] said detector and said stage are provided at different locations.
- 2. (Previously Presented) A device manufacturing apparatus according to claim 1, said detector comprising:
  - a light emitter for emitting a detection light; and
  - a receiver for receiving said detection light emitted from said light emitter;

wherein said receiver determines whether said droplet is being discharged from said discharge nozzle, based on changes in the intensity of said detection light received by said receiver due to said droplet passing through the optical path of said detection light.

- 3. (Original) A device manufacturing apparatus according to claim 2, wherein said controller performs calibration of said receiver at a predetermined timing.
- 4. (Original) A device manufacturing apparatus according to claim 1, further comprising a recovery unit for performing a recovery operation of said discharge nozzle.
- 5. (Original) A device manufacturing apparatus according to claim 4, wherein said controller performs said recovery operation corresponding to detection results of said detector, and reexecutes detection a predetermined number of times.
- 6. (Original) A device manufacturing apparatus according to claim 1, further comprising a display device for displaying detection results of said detector, and an error based on the detection results.

## 7. (Cancelled)

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- 8. (Original) A device manufacturing apparatus according to claim 1, wherein said discharge head is two or more.
- 9. (Original) A device manufacturing apparatus according to claim 1, wherein said device is at least one of; a liquid crystal element, an organic electroluminescent element, a plasma display element, an electron emission element, an optical element and a conductive film element.
- 10. (Currently amended) A device manufacturing method comprising: a step of discharging a droplet containing a functional material onto a substrate by means of a discharge nozzle in a discharge head;

a carrying step of [carrying] loading and unloading said substrate;

a step of moving said discharge nozzle from a position at which said step of discharging said droplet is carried out, to an another position at which an operation for detecting a discharge condition of said droplet which is discharged from said discharge nozzle is carried out, during said carrying step; and

a detection step of detecting said discharge condition, during said carrying step.

11. (Previously Presented) A device manufacturing method according to claim 10, comprising the steps of:

emitting detection light towards a receiver; and

determining whether said droplet is being discharged from said discharge nozzle, based on changes in the intensity of said detection light received by said receiver due to said droplet passing through the optical path of said detection light.

- 12. (Original) A device manufacturing method according to claim 11, wherein calibration of said receiver is performed at a predetermined timing.
  - 13. (Cancelled)
  - 14. (Cancelled)
  - 15. (New) A method for manufacturing a device comprising:

loading a substrate onto a stage:

discharging droplets onto the substrate from a nozzle in a discharge head;

unloading said substrate from the stage and treating the droplets to form a

structure on the substrate; and

during the loading or unloading of the substrate, testing the discharge head by passing droplets therefrom through a light beam.